

SHIGA7.055APC

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hirayama et al.
Appl. No. : U.S. National Phase of
PCT/JP2005/001798
Filed : Herewith
For : BASE MATERIAL FOR
PATTERN-FORMING
MATERIAL, POSITIVE RESIST
COMPOSITION AND METHOD
OF RESIST PATTERN
FORMATION
Examiner : Unassigned
Group Art Unit : Unknown

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all
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Alexandria, VA 22313-1450, on

August 17, 2006

(Date)

Neil S. Bartfeld, Ph.D., Reg. No. 39,901

PRELIMINARY AMENDMENT**Mail Stop PCT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

Prior to examination of the above-referenced application, please enter the following
amendments:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 5 of this paper.